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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. NOVLP068/NVLS-2818	Application No.: 10/690,084
	Applicant: Koos et al. Filing Date October 20, 2003	Group 1765

**U.S. Patent and Publication Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub- class	Filing Date
	A1						

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub- class	Translation	
							Yes	No
	B1							

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
/LV/	C1	Office Action mailed July 27, 2007, from U.S. Application No. 11/586,394 [NOVLP068X1/NVLS-2818C1]
Examiner	/Lan Vinh/	Date Considered 09/28/2007

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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## U.S. Patent and Publication Documents

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
/LV/	A1	7,049,234	05/2006	Cheng et al.			
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	<b>Group</b>	1765
		Page 1 of 1

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	1.						
	2.						
	3.						

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							Yes	No
	4.							

**Other Documents**

Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
/LV/	5.	U.S. Final Office Action mailed July 18, 2007 from U.S. Application No. 11/251,353. [NOVLP141/NVLS-3107]
/LV/	6.	SanderKok.com, "Analytical Chemistry", <a href="http://home.planet.nl/-skok/ttechniques/laboratory/pka_pkb.htm">http://home.planet.nl/-skok/ttechniques/laboratory/pka_pkb.htm</a> .

<b>Examiner</b> /Lan Vinh/	<b>Date Considered</b> 09/28/2007
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/LV/	3.	2002/0084529	07.2002	Dubin et al.			

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial		Document No.	Publication Date	Country or Patent Office	Class	Sub-Class	Translation	
							Yes	No
	4.	JP02111883	04.1990	JPO				

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Examiner Initial	No.	Author, Title, Place (e.g. Journal) of Publication, Date
/LV/	5.	Mayer et al., "Pad-Assisted Electropolishing," Novellus Systems, Inc., Appln No.: 11/213,190, filed August 26, 2005. [NVLS-3037]
/LV/	6.	Mayer et al., "Topography Reduction and Control by Selective Accelerator Removal," Novellus Systems, Inc., Appln. No.: 11/602,128, filed November 20, 2006. [NVLS-2960]
/LV/	7.	Aksu et al., "The Role of Glycine in the Chemical Mechanical Planarization of Copper," Journal of The Electrochemical Society, 149 (6) G352-G361 (200), Department of Materials Science and Engineering, University of California, Berkeley, Berkeley, California 94720-1760, USA <span style="float: right;">NO DATES</span>
/LV/	8.	U.S. Office Action mailed August 16, 2006 from U.S. Application No. 10/742,006. [NOVLP065/NVLS-2796]

Examiner	/Lan Vinh/	Date Considered	07/30/2007
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Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date
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	A2	6,692,873	11/8/05	Park			
	A3	5,824,599	10/20/98	Schacham-Diamond, et al.			
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							Yes	No
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LV	C2	Eugene J. O'Sullivan, "Electroless Deposition in Microelectronics: New Trend," Electrochemical Society Proceeding Volume 99-34, 159-171 NO PATES LV
LV	C3	T. Itabashi et al., "Electroless Deposited CoWB for Copper Diffusion Barrier Metals," Hitachi Research Laboratory, IEEE, 2002, 285-287 NO PA
LV	C4	N. Petrov and Y. Shacham-Diamand, "Electrochemical Study of the Electroless Deposition of Co(W,P) Barrier Layers for Cu Metallization," Electrochemical Soc. Proceedings Vol. 2000-27, 134-148 NO PATES LV
Examiner /Lan Vinh/		Date Considered 11/22/2006

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